



Developments in Sub-Aperture Techniques for Precision Mirror Fabrication

presented to:

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Mirror Development
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QED Technologies®

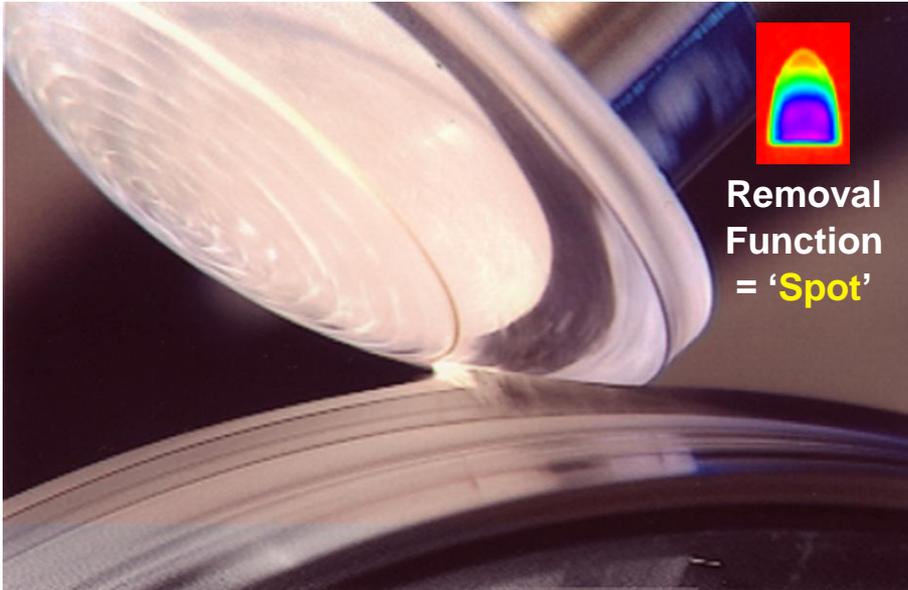
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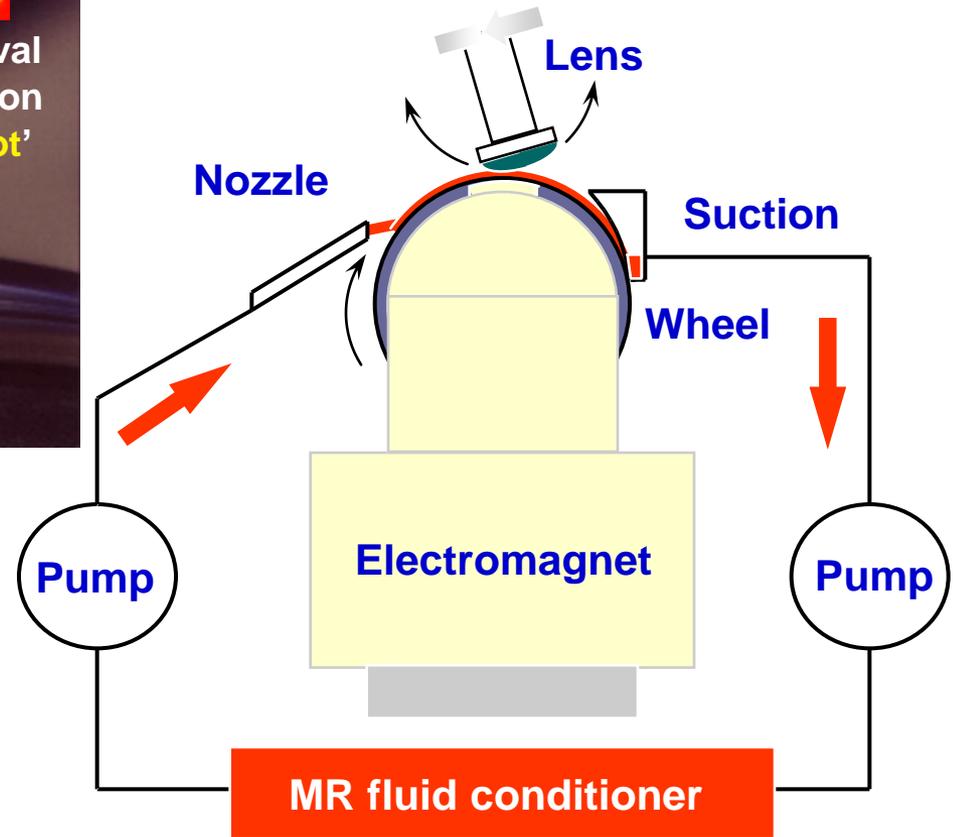
John West, John Hraba
Dr. Philip Stahl - NASA
MSFC
Scott Antonille – NASA
GSFC

- **Brief MRF[®] technology introduction**
- **Demonstration of performance of 2-meter MRF platform**
- **Increase in aspheric departure that can be measured with Sub-Aperture Stitching Interferometry (SSI_A[®])**

Magnetorheological Finishing (MRF) – How it works



MRF conforms to the workpiece surface



MRF – Breakthrough Technology

The MRF polishing tool:

- never dulls or changes
- is interferometrically characterized
- is easily adjusted
- conforms to part shape - works on complex shapes (flat, sphere, asphere, cylinder, freeform...)
- has high removal rates
- removal based on shear stress so applies very low normal load on abrasive, improving surface integrity
- determinism leads to high convergence rate

These attributes lead to a production-oriented, deterministic, computer-controlled polishing and figuring technique.

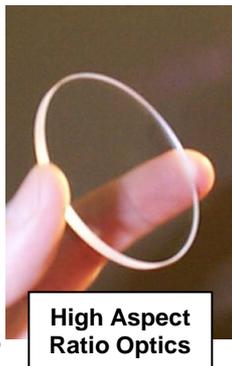
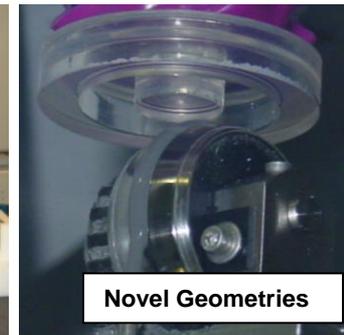
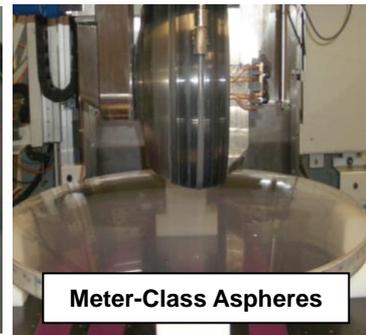
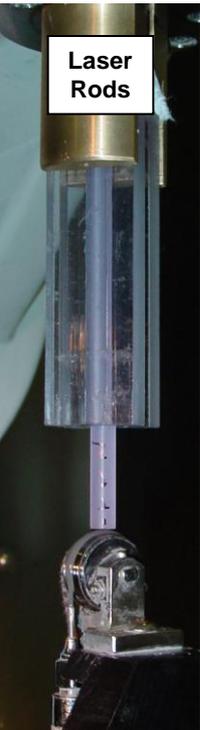
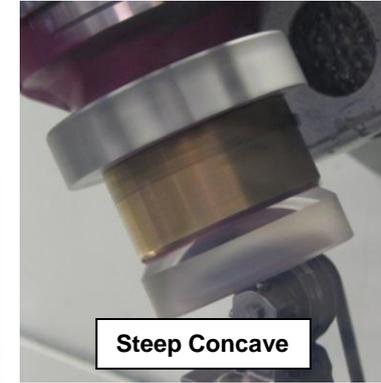
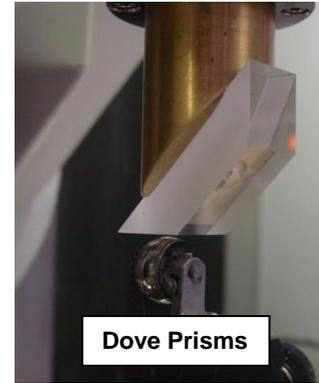
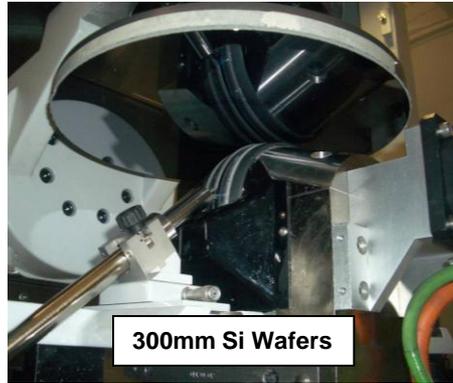
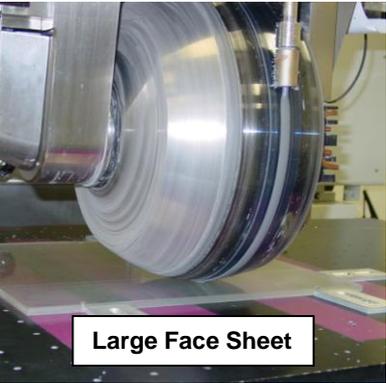
Production proven: more than 100 machines worldwide

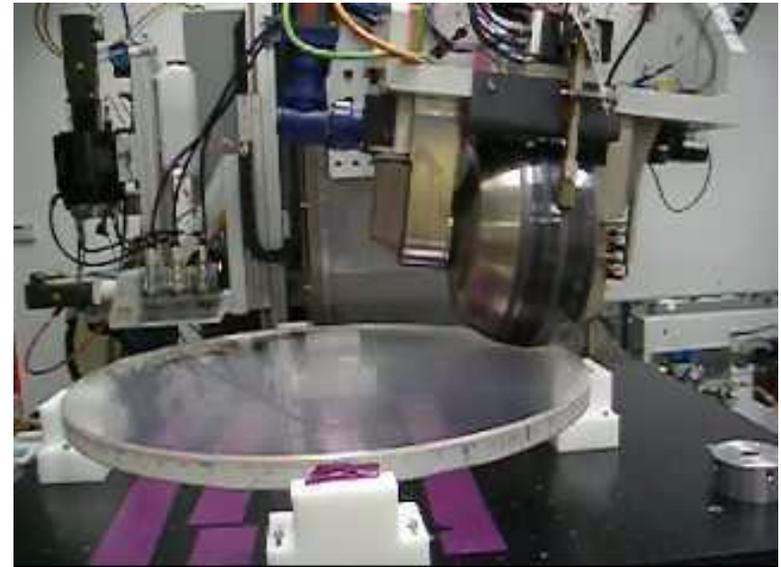
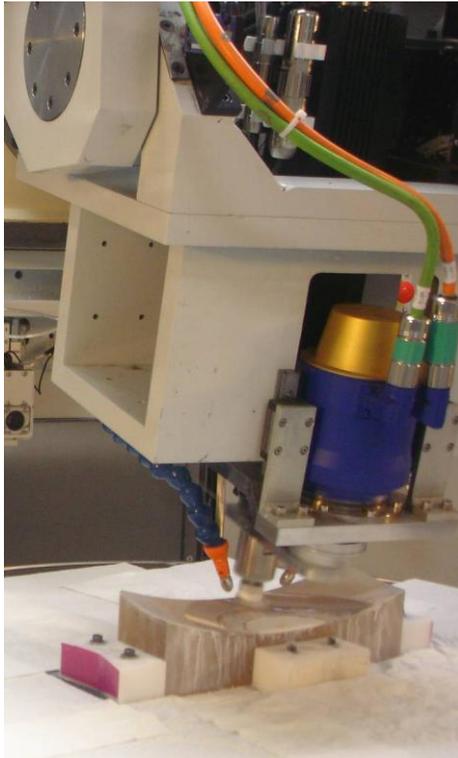
Polishing optics from 1mm to >1 meter



- **Q22-XE** – <100 mm in diameter.
- **Q22-X** - Up to 200 mm in diameter.
- **Q22-Y** - Raster tool path, up to 200 mm in size.
- **Q22-400X** - Up to 400 mm in diameter.
- **Q22-750P2** - Plano optics up to 750 mm x 1,000 mm in size.
- **Q22-950F-Polishing Center**– Freeform optics up to 950 x 1,250mm with pre-polishing capabilities
- **Q22-2000F**– Freeform optics up to 2+ meters
- **SSI[®]** -- Subaperture Stitching Interferometer (SSI) for high precision metrology.
- **SSI-A[®]** -- Subaperture Stitching Interferometer (SSI) for high precision asphere metrology.

Range of MRF Applications





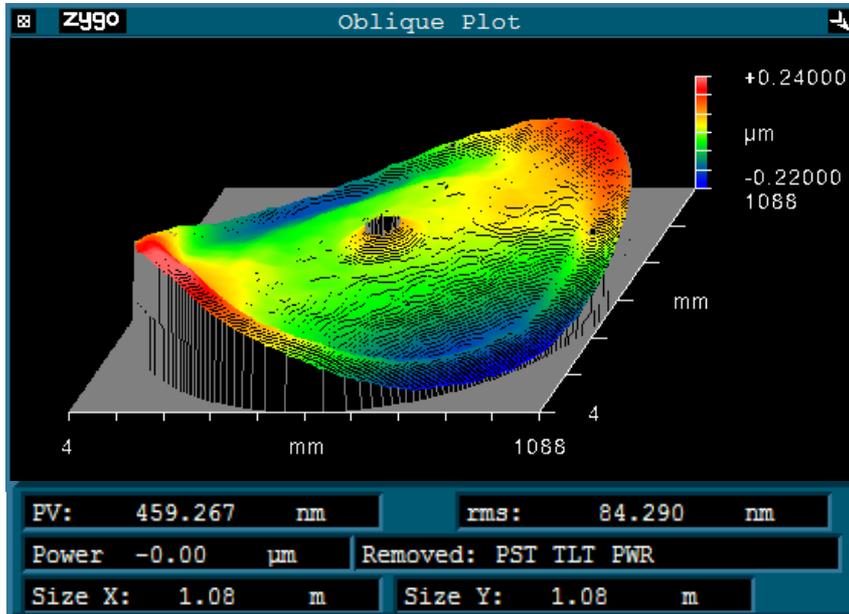
- **Q22-950F can be outfitted with pad polishing and MRF**
- **This allows the user to go from ground state to finished surface**



- 2-Meter Platform

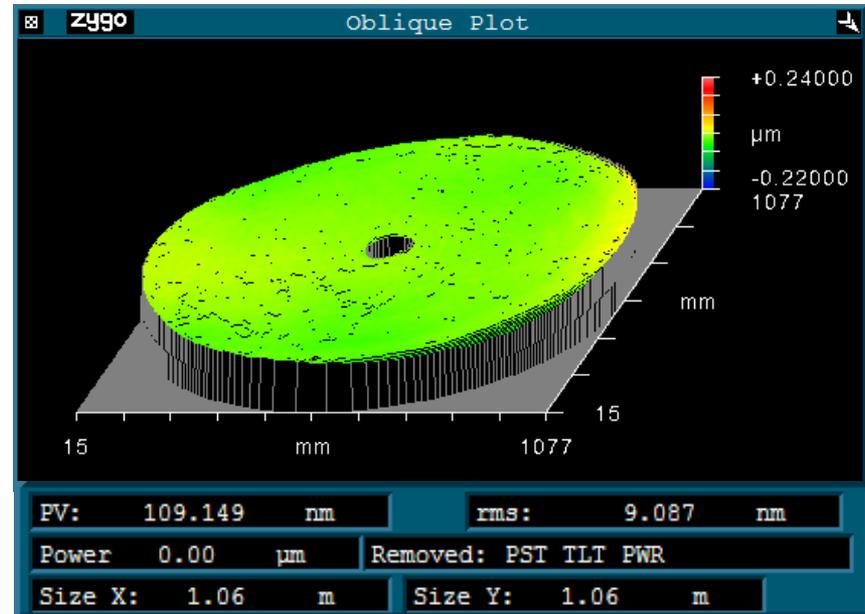
- QED has successfully delivered and installed an MRF machine capable of polishing 2-meter diameter optics
 - This machine is installed and has passed all acceptance test requirements
- **Mirror Details**
 - Outer Diameter: ~1.1 m (~43")
 - Inner Diameter: ~0.1 m (~4")
 - Radius of Curvature: ~3 m (~120")
 - Material: Low expansion material
- **Metrology**
 - Full aperture
 - Standard surface reflection test

Initial



RMS = 84 nm ($\sim\lambda/7$)

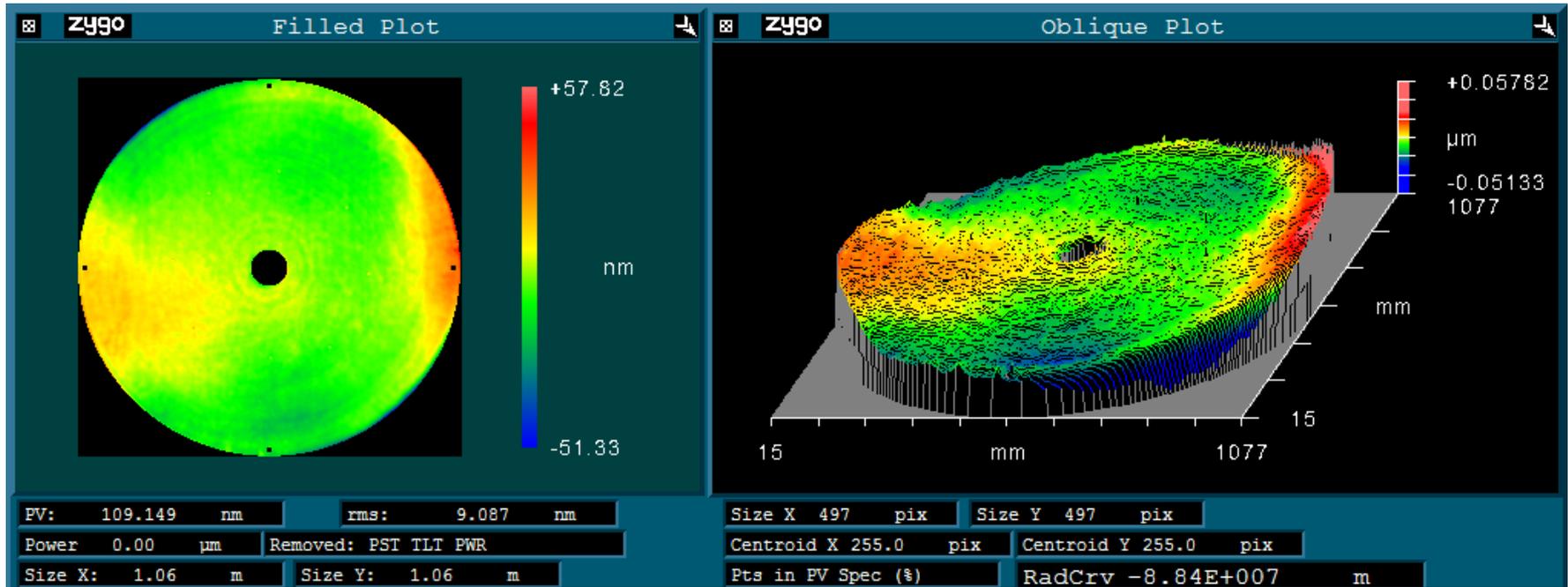
Final



RMS = 9 nm ($\sim\lambda/70$)

- Only **20 hours** of polishing time
- Only **2 iterations** of MRF

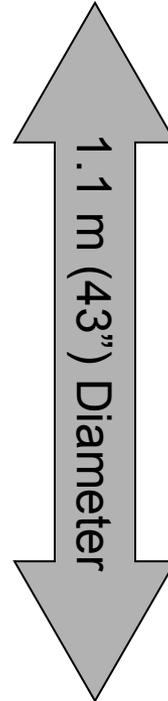
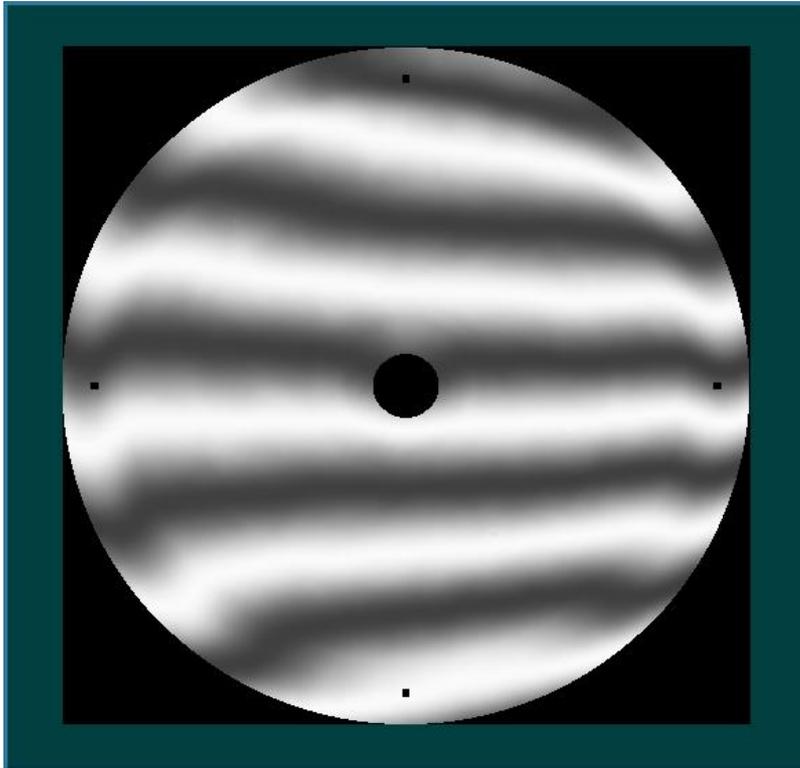
**Fast Convergence on
Meter-Class Optics!**



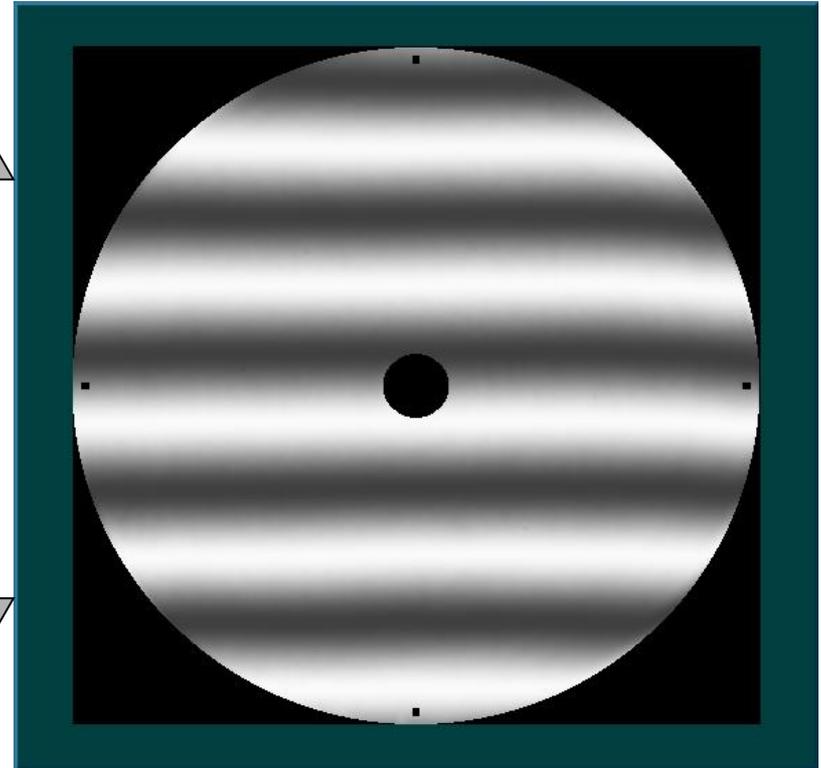
RMS = 9 nm ($\sim\lambda/70$)

- Metrology repeatability was limiting factor (due to time constraints)
- Much of residual astigmatism due to mounting distortions
- Could correct even further with improved metrology

Initial



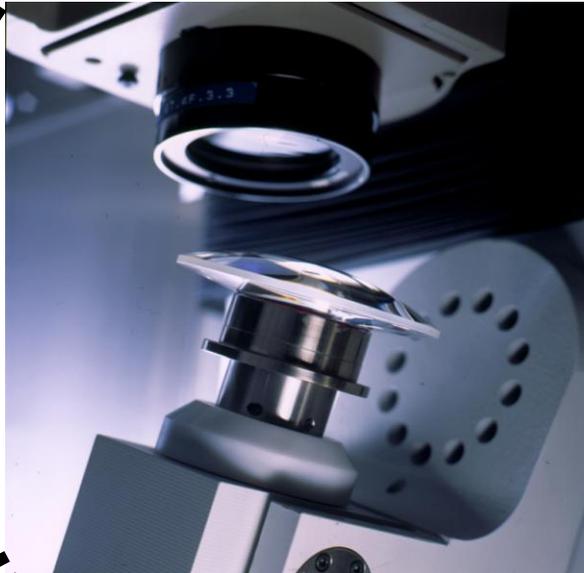
Final



- **2 MRF Iterations: 14 hrs + 6 hrs = 20 hours total**
- **Overnight, unattended operation**
- **Fast, deterministic convergence on meter-class mirrors!**

Subaperture Stitching Interferometer (SSI®)

- Precision six axis machine
- Standard Zygo® 4" or 6" interferometer
- QED control software: automation + advanced algorithms

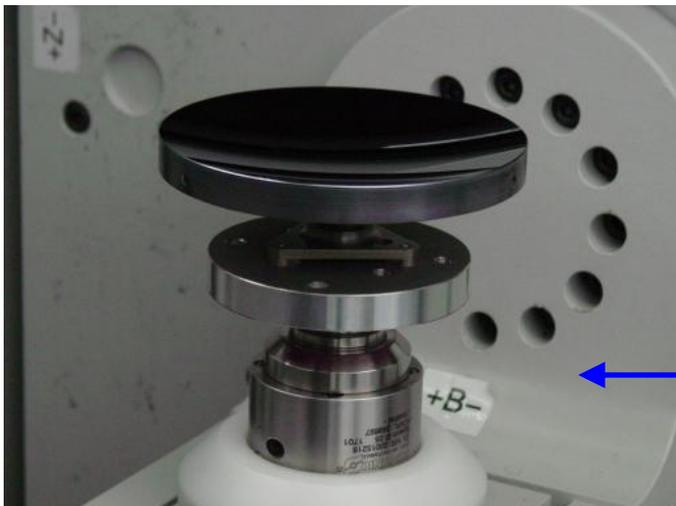
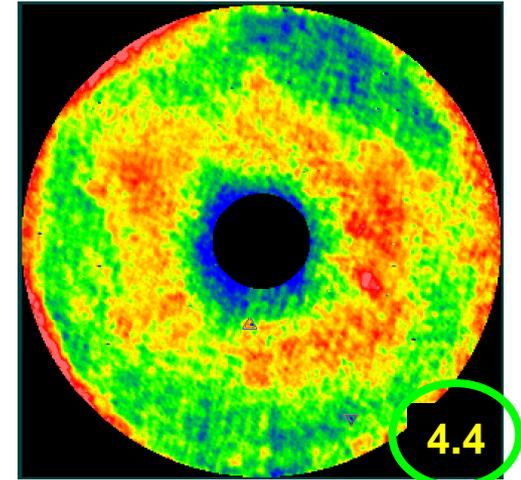


SSI advantages

- Cost-effective measurement of larger apertures
- Automatic, inline calibration of systematic error
- Increased lateral resolution
- **Measures mild aspheres without dedicated nulls!**

- R -226 mm; CA 100 mm; ~25 λ from b.f.s.
- Secondary mirror for the PICTURE / SHARPI programs
- Good agreement with vendor's null test
 - But again, note the finer structure resolved

Stitch map

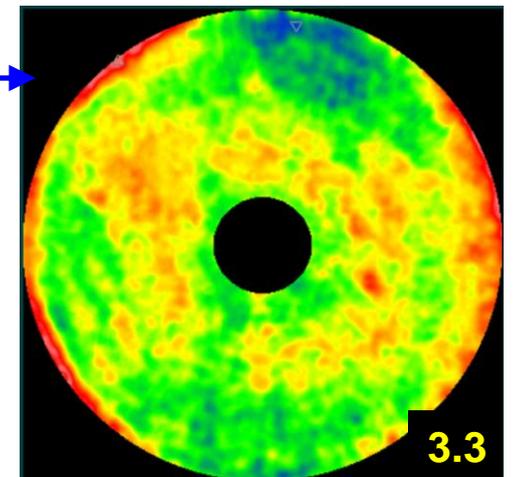


Null test data courtesy
of Jay Schwartz, L3-
SSG-Tinsley

Scale +/- 12.5 nm

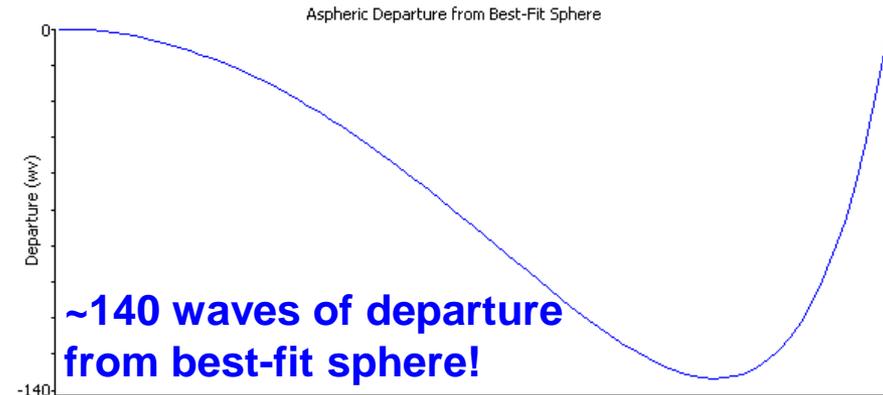
Test part courtesy of
Scott Antonille, NASA
Goddard

Conic null test



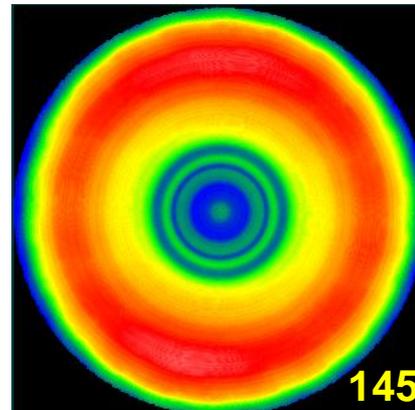
- More aspheric capability
 - Up to ~200 waves from best-fit sphere *without dedicated null lenses*
 - Aperture converter and small Transmission Spheres enable more radii and R/#s

- Enhanced usability
 - Consolidated advanced options reduces confusion
 - SSI setup wizards simplify configuring the SSI
 - and other conveniences!

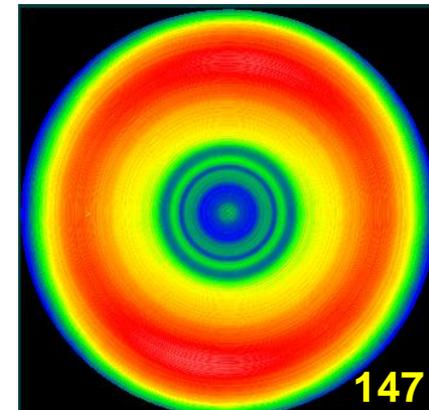


Excellent measurement reproducibility

Measurement with f/2.2

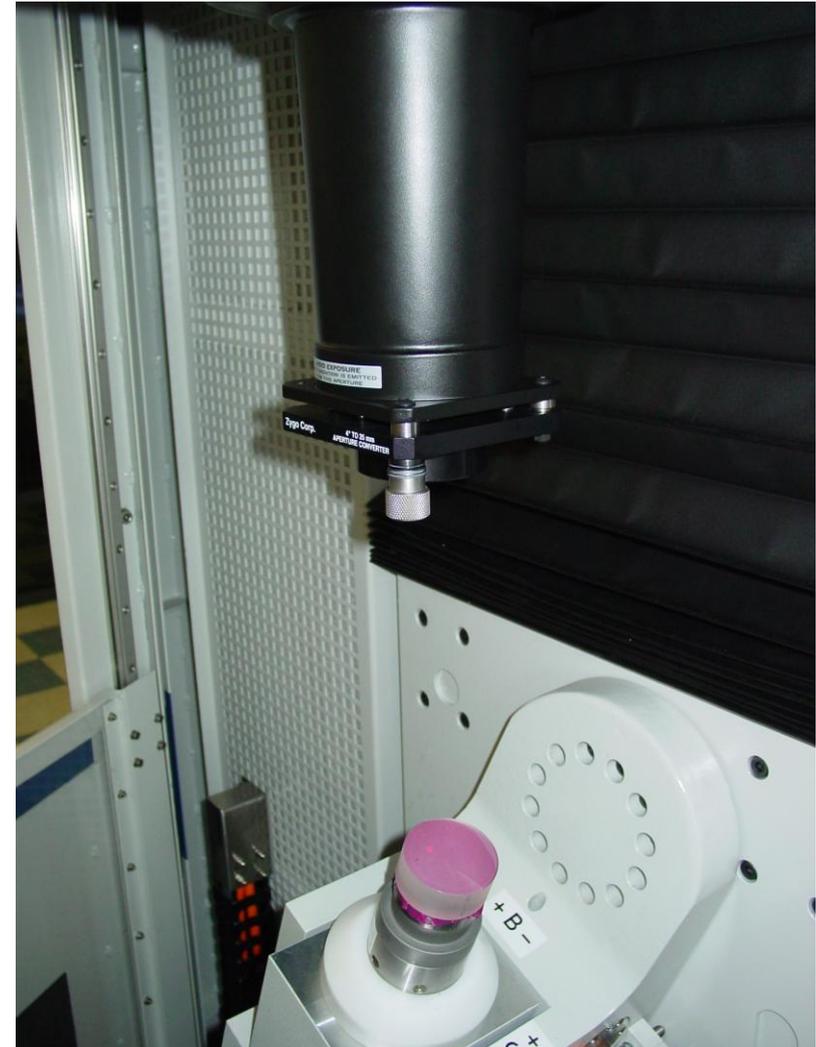


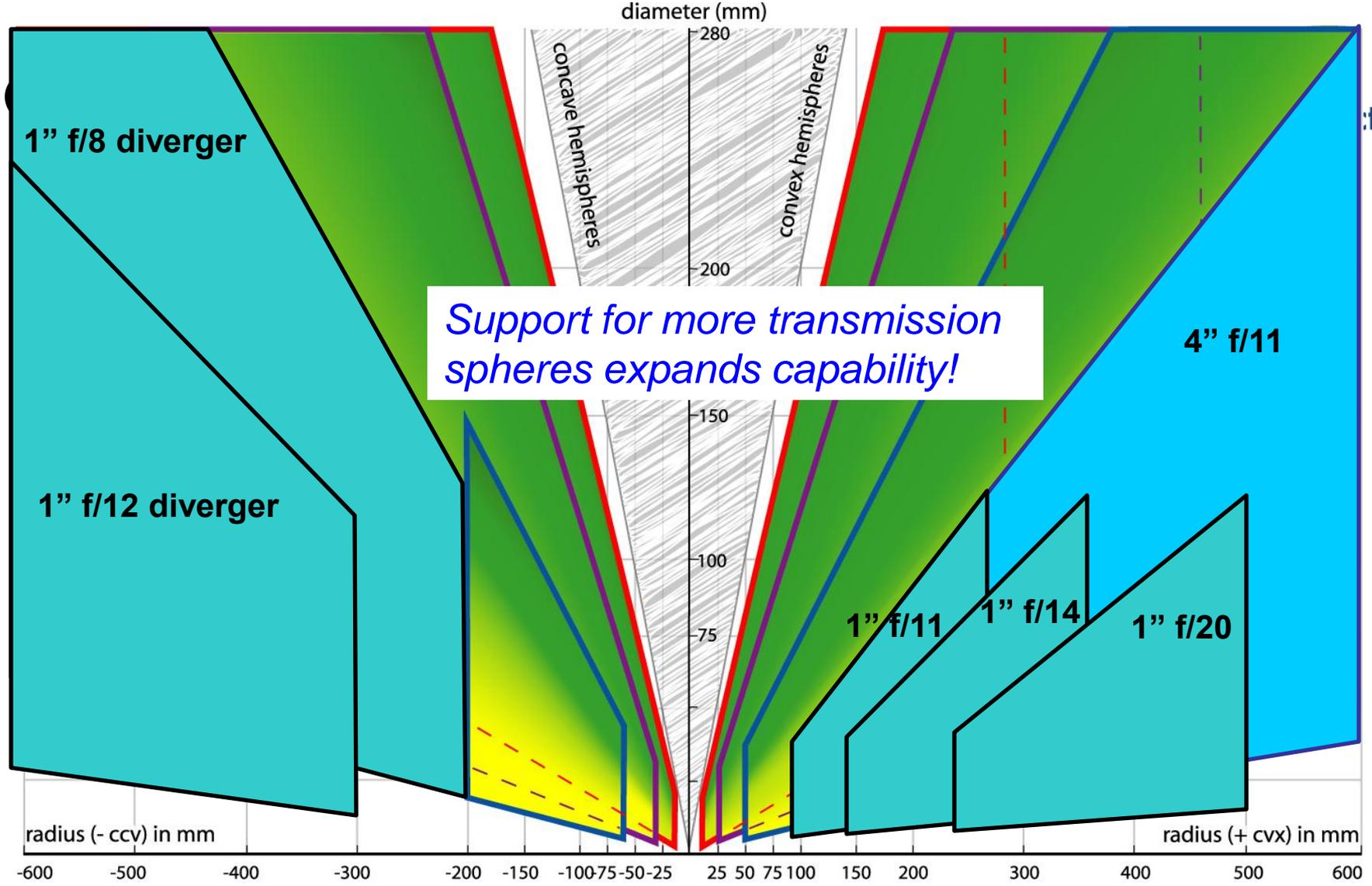
Measurement with f/3.3



Aperture converter and small transmission spheres

- Software enables use of aperture converters and small TSs
 - Higher magnification; more aspheric departure possible
 - Enables more parts to fit within the SSI 1 meter-long envelope



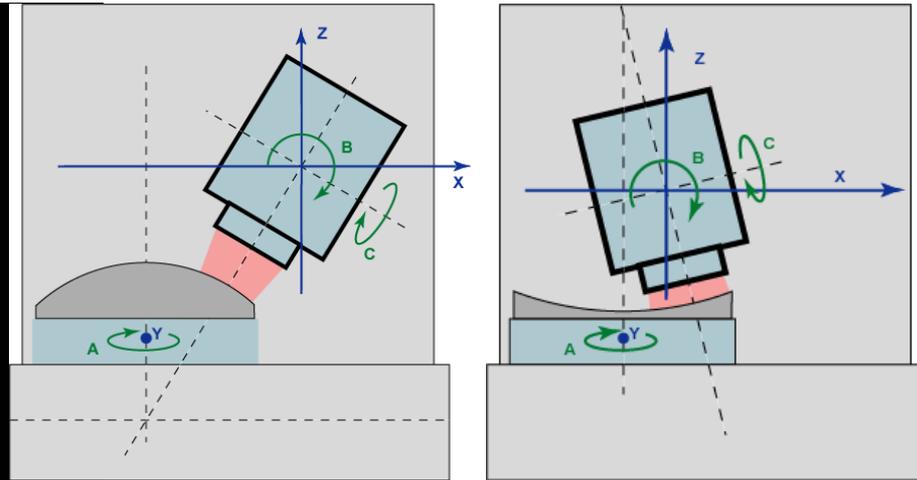
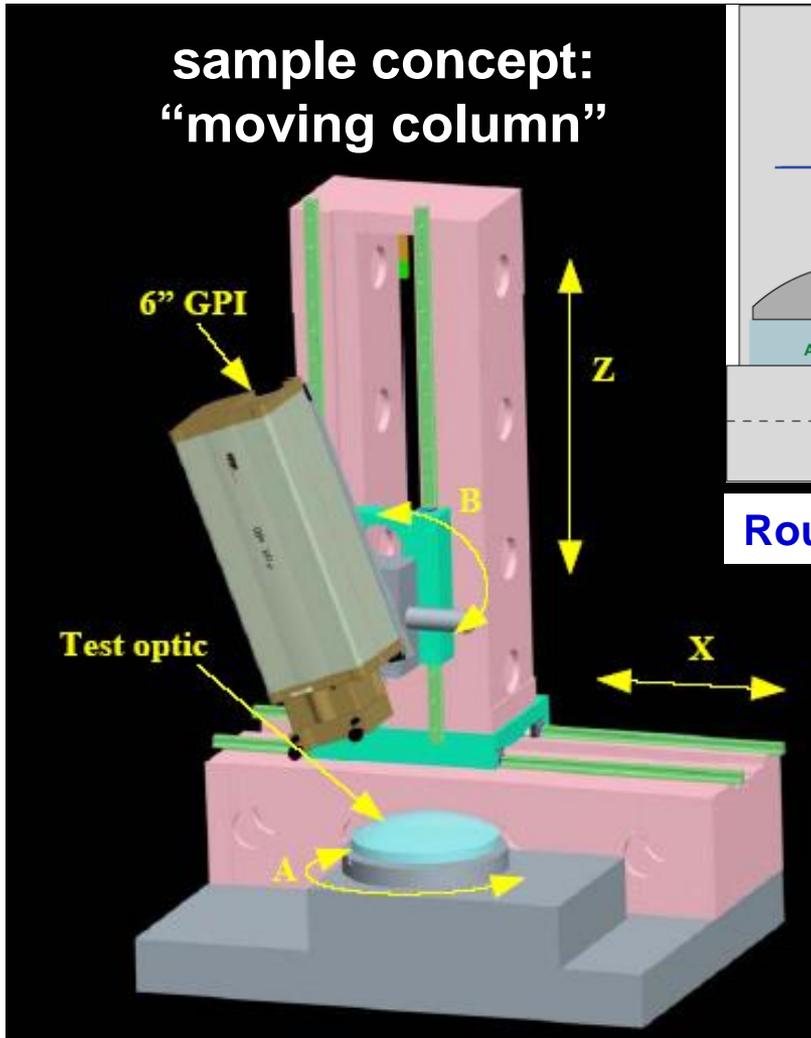


Support for more transmission spheres expands capability!

	4" f/7.2 and 6" f/5.3 (blue border)		recommended for aspheric departure up to 50 λ (yellow shading)		beyond hemispheres (not applicable)
	4" f/3.3 and 6" f/2.2 (red border)		recommended for aspheric departure up to 100 λ (green shading)		
	6" f/3.2 (purple border)				

- Benefits specific to large optics
 - Avoid fabrication of huge transmission spheres and null optics for convex surfaces (e.g. secondary mirrors)
 - No dedicated nulls (and painful calibration of them) for mild to moderate aspheric departures
 - Reduced cavity lengths (and air turbulence) for concave optics (via use of diverging TSs)
 - Improved spatial resolution (for edges and MSFs)
- Scaling up involves significant hardware changes
 - Increased size, larger X travel; tilt the interferometer, not the part
 - Need to avoid the greater mechanical distortions for large parts
 - Interferometer size selection has some trade-offs
 - 6" mainframe: lower cost (especially for TSs), easier to move
 - Cycle times and possible accuracy trade-offs
 - (e.g. for a 1.5 m segment, 6":~400 subapertures; 12": ~100)

sample concept:
"moving column"



Rough schematics of tilting interferometer

Stitching technology is scalable to larger optics in both vertical and horizontal configurations.

- Unique attributes of MRF give it the flexibility for polishing complex shapes to high precision with excellent convergence rates
- QED continues to extend the aperture size that can be finished and recently installed and demonstrated performance of a 2-meter freeform platform
 - Precision finishing of a mirror > 1 meter in size was demonstrated – 2 iteration, 20 hours of polishing
 - Very fast convergence and short cycle times demonstrated on meter-class optics
- Increased aspheric departure can now be measured using stitching interferometry (SSI_A) - ~ 200 waves of departure
- Stitching interferometry can be scaled to address meter class optics
- QED remains committed to delivering state-of-the-art solutions for optics fabrication challenges



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